

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



Applicant : YEH  
Application No. : 10/601,701  
Filed : June 24, 2003  
Title : METHOD FOR FABRICATION OF  
POLYCRYSTALLINE SILICON THIN  
FILM TRANSISTORS  
Group Art Unit : 2812  
Examiner : S. Isaac  
Docket No. : 3230-56

**MAIL STOP AMENDMENT**  
Honorable Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**AMENDMENT**

Sir:

In response to the Office Action of May 25, 2005, the period for response to which has been extended to expire on **October 25, 2005** by the filing herewith of a Petition for a two-month extension of time and payment of the required fee, please amend the above-identified application as follows:

*Interested*  
*10/1/05*  
*11-25-05*  
*Amended (in 11-30-05)*